

## Fabrication of Multi-Bit Data Storage Memories Based on Multilayer MoS<sub>2</sub>

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Molybdenum disulfide (MoS<sub>2</sub>) recently emerged as a promising material candidate for making non-volatile memory devices with fast speed and low cost.<sup>[1]</sup> A great deal of research effort has been invested to create MoS<sub>2</sub>-based memory devices based on existing flash-memory transistor structures, which need complicated heterostructures, hybrid organic/inorganic materials, precise deposition of multiple material layers, and multiple overlay lithography processes to define floating gates, blocking and tunneling layers.<sup>[1-5]</sup> Such MoS<sub>2</sub>-based memory fabrication solutions indeed increase complexity and cost of memory cells and are not advantageous over state-of-the-art memory fabrication processes at all. Therefore, new device structures and fabrication processes based on MoS<sub>2</sub> and atomically layered 2D materials are needed for enabling low-cost and upscalable memory solutions.

We present a new fabrication solution for making MoS<sub>2</sub>-based floating-gate-free, non-volatile, multi-bit memory field-effect transistors (FETs) with a unique combination of excellent retention/endurance property, extremely simple structure, and low cost.

The new multi-bit memory FETs are fabricated by using our recently developed plasma-assisted doping technique (Fig. 1).<sup>[6]</sup> Using such MoS<sub>2</sub> FETs, we have demonstrated highly reliable binary and 2 bit (*i.e.*, 4 data levels) data states with potential for year-scale data retention (Fig. 2), as well as 3 bit (*i.e.*, 8 data levels) data states at least suitable for day-scale storage (Fig. 3). Such a new multi-bit memory capability is attributed to plasma-induced mechanical separation of plasma-doped MoS<sub>2</sub> layers from undoped pristine layers, which forms an ambipolar charging layer interfacing a pristine MoS<sub>2</sub> transistor channel through a tunneling barrier, therefore resulting in multiple memory states with a broad range of energies. The full presentation will also include our in-depth electric force microscopy (EFM) characterizations of MoS<sub>2</sub> multi-bit memory FETs, which provides additional scientific insights about the setting (or charging/discharging) schemes in such memories.

This work greatly leverages the unique structural property of MoS<sub>2</sub> and other atomically layered 2D materials for applications in the fields related to data storage technologies. The presented fabrication methods and device structures hold a significant potential to be further developed into a low cost, upscalable memory solution for making future high-performance disposable electronic products such as electronic labels, digital newspapers, medical care tags, and point-of-care biosensors.

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- [6] Chen, Mikai, et al. "Stable few-layer MoS<sub>2</sub> rectifying diodes formed by plasma-assisted doping." *Applied Physics Letters* 103.14 (2013): 142110.

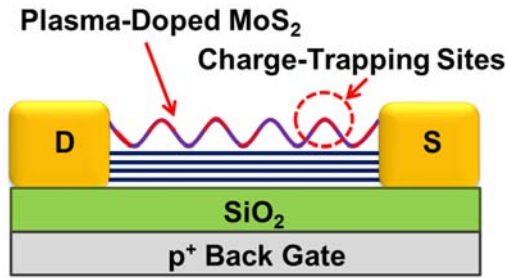


Fig. 1 Fabrication of MoS<sub>2</sub>-based multi-bit memory FET by using plasma-assisted doping processes.

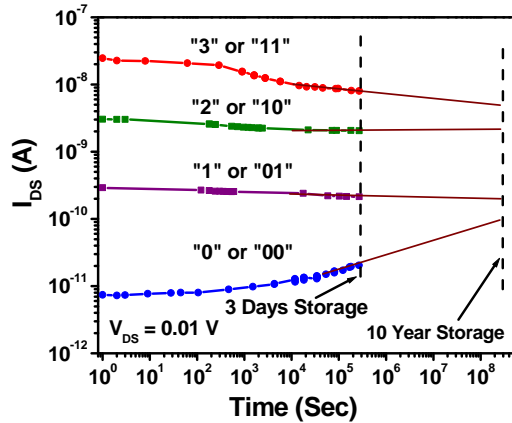


Fig. 2 Retention characteristics of 4 data states recorded for 3 days. For these 4 retention measurements,  $V_{DS} = 0.01$  V,  $V_G = 0$  V. It is estimated that these 4 data states can be well discernible within 10 years since the initial applications of programming  $V_G$  signals.

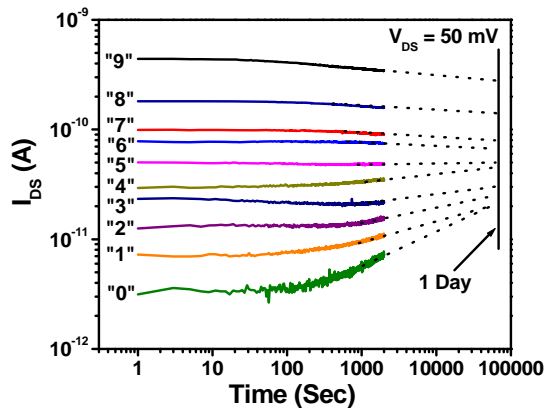


Fig. 3 Retention characteristics of 10 data states recorded for 2000 s, which are estimated to be well discernible within hour- or day-scale time durations after the initial setting.